

MPI TS200-HP | 200 mm Manual Probe System

For accurate and reliable High Power measurements up to 10kV, 600A

Light Curtain

- Interlock-enabled safety light curtain protects users from accidental high voltage shock
- Interface panel for Keysight B1505A & Keithley instrumentation

Anti-Arcing Technologies

- ArcShield™ to prevent arcing between chuck and probe platen
- LiquidTray™ to safely place the wafer for high voltage test in arcing suppressing liquid

MicroPositioners

- Supports up to 4 high current and 8 high voltage positioners
- Various positioners available
- Dedicated Coax and Triax high voltage and high current probe arms

Probe Platen

- Fine adjustment of platen height up to 20 mm, with 1 mm scale
- Supports DC/CV, RF and High Power measurements
- Rectangular adjustments for RF MicroPositioners
- Integrated probe platen air-cooling for maximum thermal stability

Unique Platen Lift

- Three discrete positions for contact, 300 µm separation and 3 mm safety loading
- Safety lock function at loading position
- “Auto Contact” position with 1 µm repeatability
- Additional stop at 50, 100 or 150 µm alignment height

ShieldEnvironment™

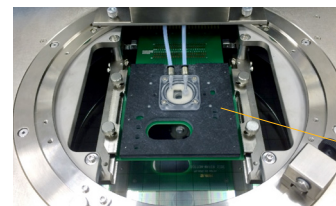
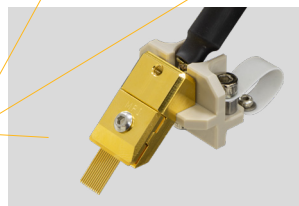
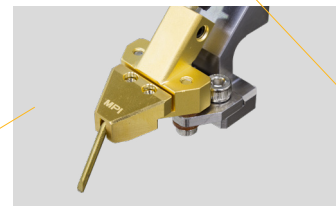
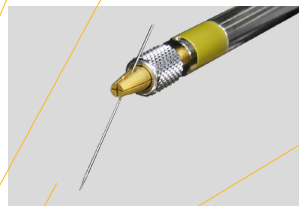
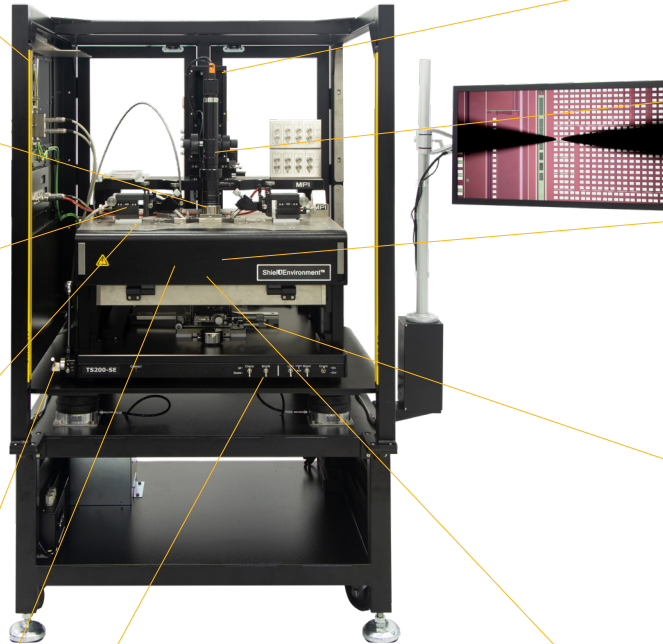
- Advanced EMI and light-tight shielded test environment for ultra-low noise, low capacitance measurements
- Front door for manual loading of IC or wafers ShieldDCap™
- Automated front door lock function for safe ice-free testing

Front Mounted Vacuum Control

- Easy access and clearly marked
- Integrated active vibration isolation table

High Power Probes

- High voltage, low leakage probes up to 10 kV
- High current, multi-fingers probes up to 200 A (pulse)
- Ultra high power, multi-fingers probes up to 10kV/600A (pulse)



Microscope Mount and Movement

- Stable bridge for high quality optics
- 50 x 50 mm linear XY movement
- Linear z lift for easy reconfiguration

Microscope and Optics

- Single tube MPI SZ12, MZ12
- Up to 12x zoom and 101 mm working distance
- HDMI cameras, monitor user interface without computer

Modular Chucks

- Various High Power non-thermal or thermal chucks
- Wide range of temperature from -60 °C up to 300 °C
- Field upgradable for reduced cost of ownership
- Thin wafer handling capability
- 10 kV (Coax), 3kV (Triax)
- Gold plated for low contact resistance
- MPI 10kV chuck connectors for safe instrument connection
- Re-use chuck cooling air for chamber purge

Chuck XYZ Stage Movement

- Unique puck-controlled air bearing stage for chuck single-handed operation
- 225 x 260 mm XY total stage movement
- 25 x 25 mm XY fine micrometer adjustment
- Resolution < 1.0 µm (0.04 mils) @ 500 µm/rev
- Chuck theta rotation of 360° with +/-5° fine travel
- Safe contact function locks the XY stage while in contact
- 20 mm pneumatically Z load stroke,
- 5 mm fine Z, resolution < 1.0 µm @ 500 µm/rev
- Extra wide Y-range for easy wafer loading
- Optional independent lock of the X or Y axis

Safety Test Management™ (STM) System

- Provides unique safety, reliable and convenient environment for testing at different temperatures
- Intelligent dew point control routine avoids acumination during cold testing
- Automatically monitoring the flow of CDA or Nitrogen
- If the flow is interrupt or insufficient the STM™ turns the chuck automatically into safe mode

Anti-arcing probe card

- High pressure application for testing up to 10 kV/600A
- Temperature testing up to 150 °C